



PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER ART UNIT 2818**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kiyoichi SUWA

Group Art Unit: 2818

Application No.: 09/729,339

Examiner: Q. Hoang

Filed: December 5, 2000

Docket No.: 108057

For: MASK, EXPOSURE METHOD, LINE WIDTH MEASURING METHOD, AND
METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICES

AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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FEB 23 2004

Sir:

In reply to the August 27, 2003 Office Action, the shortened statutory period for reply
being extended by the attached Petition for Extension of Time, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.